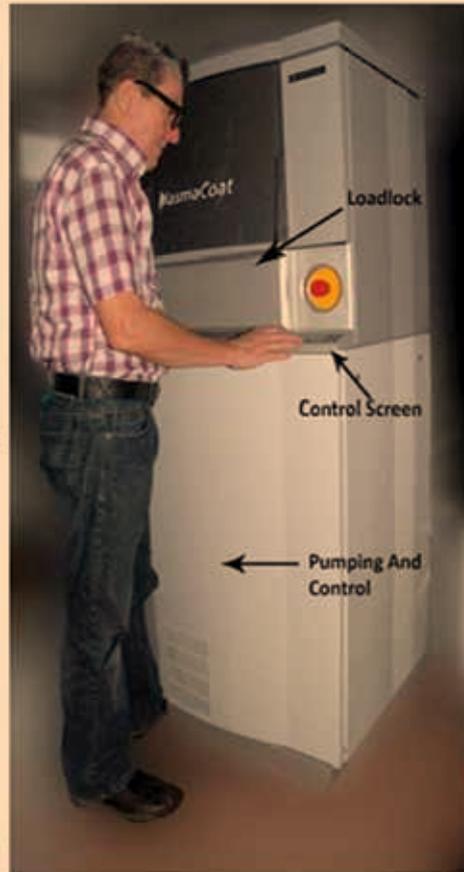
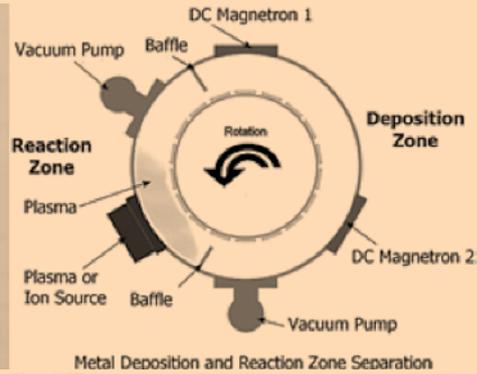
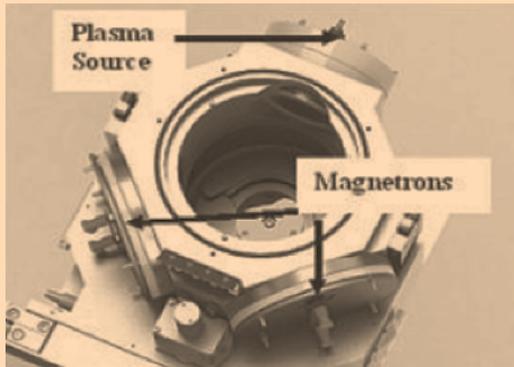


Active Research and Consultancy in

SMALL BATCH HIGH THROUGHPUT PLASMA ACTIVATED MAGNETRON SPUTTERING SYSTEM

Loadlock based DC magnetron sputter deposition system, capable of deposition of metals, oxides and transparent conductive oxides. Maximum substrate size 80mm diameter.



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